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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **OZAKI, Takashi, et al.**

Group Art Unit: 1792

Serial No.: 10/528,137

Examiner: **MACARTHUR, Sylvia**

Filed: **December 12, 2005**

P.T.O. Confirmation No.: 2307

**FOR: SUBSTRATE PROCESSING APPARATUS AND METHOD FOR
MANUFACTURING A SEMICONDUCTOR DEVICE**

RESPONSE UNDER 37 CFR §1.116

- EXPEDITED RESPONSE -

GROUP ART UNIT 1792

MAILSTOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 23, 2009

Sir:

In response to the Final Office Action dated **October 2, 2008**, extended from **January 2, 2009 to February 2, 2009** by a **one (1) month** Petition for Extension of Time, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 9 of this paper.